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From: Ira Matsil **Date:** June 16, 2004
Pages: 4

Applicant: Schulze, *et al.* **Docket No:** 115747-0003//2002P50544US

Serial No.: 10/753,604 **Art Unit:** 1762

Filed: January 8, 2004 **Examiner:** TBD

For: Method for the Repair of Defects in Photolithographic Masks for Patterning
Semiconductor Wafers

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Schulze, *et al.* Docket No.: 115747-0003//2002P50544US
Serial No.: 10/753,604 Art Unit: 1762
Filed: January 8, 2004 Examiner: TBD
Title: Method for the Repair of Defects in Photolithographic Masks for Patterning
Semiconductor Wafers

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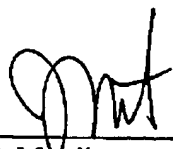
REQUEST FOR CORRECTION

Sir:

Petitioner hereby requests a correction in the Filing Receipt of the above-referenced patent application. Enclosed is a copy of the Filing Receipt with the change to the Title noted.

Respectfully submitted,

June 16, 2004
Date



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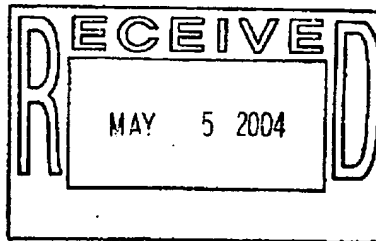
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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/753,604	01/08/2004	1762	1446	115747-0003//2002P50544US	3	48	5

007470
WHITE & CASE LLP
PATENT DEPARTMENT
1155 AVENUE OF THE AMERICAS
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CONFIRMATION NO. 6349

FILING RECEIPT



OC000000012391381

Date Mailed: 04/19/2004

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Filing Receipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

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Enio L. Carpl, Round Rock, TX;

WHITE & CASE LLP
PATENT DEPARTMENT

APR 22 2004

RECEIVED

Domestic Priority data as claimed by applicant

Foreign Applications

If Required, Foreign Filing License Granted: 04/19/2004

Projected Publication Date: To Be Determined - pending completion of Missing Parts

Non-Publication Request: No

Early Publication Request: No

Title

photolithographic
Method for the repair of defects in photolithographic masks for patterning semiconductor wafers

Preliminary Class

427

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